

Docket No. 221158US2PCT



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Yasutaka ITO, et al.

SERIAL NO: 10/088,098

GAU: 3742

FILED: May 30, 2002

EXAMINER: S. Fuqua

FOR: CERAMIC SUBSTRATE FOR SEMICONDUCTOR MANUFACTURE/INSPECTION APPARATUS, CERAMIC HEATER, ELECTROSTATIC CLAMPLESS HOLDER, AND SUBSTRATE FOR WAFER PROBER

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97

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COMMISSIONER FOR PATENTS  
ALEXANDRIA, VIRGINIA 22313

MAR 5 - 2004

SIR:

Applicant(s) wish to disclose the following information.

**GROUP 3600**

REFERENCES

- The applicant(s) wish to make of record the references listed on the attached form PTO-1449. Copies of the listed references are attached, where required, as are either statements of relevancy or any readily available English translations of pertinent portions of any non-English language references.
- A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

RELATED CASES

- Attached is a list of applicant's pending application(s) or issued patent(s) which may be related to the present application. A copy of the patent(s), together with a copy of the claims and drawings of the pending application(s) is attached along with PTO 1449.
- A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

CERTIFICATION

- Each item of information contained in this information disclosure statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.
- No item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this statement.

DEPOSIT ACCOUNT

- Please charge any additional fees for the papers being filed herewith and for which no check or credit card payment is enclosed herewith, or credit any overpayment to deposit account number 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,  
MAIER & NEUSTADT, P.C.

  
Gregory J. Maier  
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MAR 02 2004

SHEET 1 OF 2

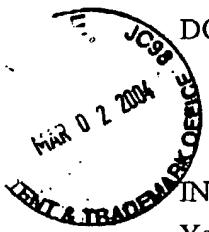
Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 221158US2PCT	SHEET 1 OF 2 SERIAL NO. 10/088,098		
LIST OF REFERENCES CITED BY APPLICANT		APPLICANT Yasutaka ITO, et al.					
		FILING DATE May 30, 2002		GROUP 3742			
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
Sgt	AA	4,621,064	11/4/1986	MATSUURA ET AL.	—	—	
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
RECEIVED MAR 15 2004 TECHNOLOGY CENTER R3700							
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
Sgt	AJ	6-157132 E	06/03/1994	JAPAN (w/ English Abstract)	XX		
	AK	58-218143	12/19/1983	JAPAN (w/ English Abstract)	XX		
	AL	EP 0 743 290 A1	11/20/1996	EUROPE (w/ English Translation of PCT Publication No. WO95/21139)			
	AM	EP 0 771 772 A2	05/07/1997	EUROPE (w/ English Abstract and corresponding English Translation of JP 10-72260)			
	AN	EP0798278	10/1/1997	EUROPE (w/ English Abstract only and corresponding U.S. Patent No. 6,001,760 and corresponding JP 9-315867-no translation)			
	AO	6 151332	05/31/1994	JAPAN (w/ English Abstract and full text translation)	XX		
	AP	5-330924	12/14/1993	JAPAN (w/ English Abstract and full English text translation)	XX		
	AQ	6-80473	3/22/1994	JAPAN (w/ English Abstract and full English text translation)	XX		
	AR	6-219844	08/09/1994	JAPAN (w/ English Abstract and full English text translation)	XX		
V	AS	7-187620	07/25/1995	JAPAN (w/ English Abstract and full English text translation)	XX		
Sgt	AT	6-219848	08/09/1994	JAPAN (w/ English Abstract and full English text translation)	XX		
	AU						
	AV						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
Sgt	AW	T. Fawcett, The American Ceramic Society Bulletin, Vol. 75, No. 10, pgs. 76-80, "Raw Materials Influence the Alpha-Particle Emission Rate of AlN", October 1996.					
	AX	Japanese w/ English translation of Experimental report (exhibit 4)					
	AY	Japanese w/ English translation of Experimental report (exhibit 5)					
Sgt	AZ	Japanese w/ English translation of Analysis and experimental report (exhibit 6)				<input checked="" type="checkbox"/> Additional References sheet(s) attached	
Examiner	Shawntera S. Fugna				Date Considered 6/26/07		
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

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SHEET 2 OF 2

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY DOCKET NO. 221158US2PCT	SERIAL NO. 10/088,098
LIST OF REFERENCES CITED BY APPLICANT		APPLICANT	Yasutaka ITO, et al.	
		FILING DATE May 30, 2002	GROUP 3742	
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)				
<i>Sff</i>	AAA	Japanese w/ English translation of Analysis and experimental report (exhibit 7)		
	AAB	Japanese w/ English translation of Ceramic Data Book (portion) page 68, 1993 (cited as exhibit 8)		
	AAC	Japanese w/ English translation of New Ceramics & Electronic Ceramics, Vol. 11, No. 9, pgs. 13-18, "New Ceramics" 1998		
	AAD	Japanese w/ English translation of Electric Materials, pgs 51-57, "Electrostatic chuck and its application", July 1996		
	AAE	Japanese w/ English translation of New Materials-Technology & Applications, Vol. 3, No. 4, pgs 51-53, April, 1992		
	AAF	Japanese w/ English translation of Electronic Ceramics , Vol. 22, No. 104, pgs 51-54, 1991		
	AAG	Japanese w/ English translation of Bulletin of the Ceramic Society of Japan, Vol. 26, No. 8, pgs. 733-737, "Ceramics", 1991		
	AAH	Japanese w/ English translation of Bulletin of the Ceramic Society of Japan, Vol. 29, No. 8, pgs 679-681, "Ceramics", 1994		
	AAI	Japanese w/ English translation of JFCA Fine Ceramics Catalogues, page 48, (Raw material, Secondary material, Material, Parts, Manufacturing/Processing device, Measurement/Evaluation device, Service), 1996		
<i>✓</i>	AAJ	Japanese w/ English translation of Journal of the Society of Powder Technology, Japan, Vol. 34, No. 8, pgs. 610-616, "Thus a powder is produced", 1997		
<i>Sff</i>	AAK	Japanese w/ English translation of Fine Ceramics Report, Vol. 15, No. 10, pgs. 226-230, 1997		
	AAL			
	AAM			
	AAN	<b>RECEIVED</b>		
	AAO	MAR 15 2004 TECHNOLOGY CENTER R3700		
	AAP			
	AAQ			
Examiner <i>Shawntina Jague</i>			Date Considered <i>6/26/04</i>	
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.				

DOCKET NO.: 221158US2PCT



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**IN RE APPLICATION OF:**

Yasutaka ITO, et al.

SERIAL NO: 10/088,098

GROUP: 3742

FILED: May 30, 2002

EXAMINER: S. T. Fuqua

FOR: CERAMIC SUBSTRATE FOR SEMICONDUCTOR  
MANUFACTURE/INSPECTION APPARATUS, CERAMIC HEATER,  
ELECTROSTATIC CLAMLESS HOLDER, AND SUBSTRATE FOR WAFER  
PROBER

**STATEMENT OF RELEVANCY**

AA- US 4,621,064 which was cited in the Office action of the  
US Patent Application No. 10/048,490 (O/FileIB240US)

AJ- Full text translation of JP H6-157132, which is cited in  
the notification of the rejection for JP Appl. H11-377207

AK- Full text translation of JP S58-218143, which is cited  
in the notification of rejection for JP Appl. H11-377207

AL- EP 0743290, which contains translation of W095/21139, cited  
in the written objection to JP Appl. H11-377207 by NGK as exhibit  
1.

AM- EP0771772, which contains translation of JP H10-72260,  
cited in the written objection to JP Appl. H11-377207 by NGK  
as exhibit 2.

AN- EP 0798278, which contains translation of JP H9-315867,  
cited in the written objection to JP Appl. H11-377207 by NGK  
as exhibit 2.

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MAR 5 - 2004  
**GROUP 3600**

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MAR 15 2004  
TECHNOLOGY CENTER R3700

AO- Full text translation of JP H6-151332, which is cited in the written objection to JP Appl. H11-377207 by Morita

AP- Full text translation of JP H5-330924, which is cited in the written objection to JP Appl. H11-377207 by Morita

AQ- Full text translation of JP H6-80473, which is cited in the written objection to JP Appl. H11-377207 by Morita

AR- Full text translation of JP H6-219844, which is cited in the written objection to JP Appl. H11-377207 by Morita

AS- Full text translation of JP H7-187620, which is cited in the written objection to JP Appl. H11-377207 by Morita

AT- Full text translation of JP H6-219848, which is cited in the written objection to JP Appl. H11-377207 by Morita

AW- 'Raw material influence the alpha-particle emission rate of AlN' which was submitted in the written opinion by Ibiden in opposition to the written objection to Japanese Patent Application H11-377207 (O/File:IB231, which is a basis of the priority right of the related PCT application, 0/File:IB240W0, of this case) by NGK

AX- Translation of Experimental report (exhibit 4), cited in the written objection to JP Appl. H11-377207 by NGK with its explanation.

AY- Translation of Experimental report (exhibit 5), cited in the written objection to JP Appl. H11-377207 by NGK with its explanation.

AZ- Translation of Analysis and experimental report (exhibit 6) cited in the written objection to JP Appl. H11-377207 by NGK with its explanation.

AAA- Translation of Analysis and experimental report (exhibit 7) cited in the written objection to JP Appl. H11-377207 by NGK with its explanation.

AAB- Translation of Ceramic data book (portion) which is cited in the written objection by NGK

AAC- Translation of pages 13 to 18 of "Volume 11 Number 9 in 1998 of New ceramics" which is cited in the written objection to JP Appl. H11-377207 by Kyocera

AAD- Translation of pages 51 to 57 of "Electric materials (Electrostatic chuck and its application) issued in July, 1996", which is cited in the written objection to JP Appl. H11-377207 by Kyocera

AAE- Translation of pages 51 to 53 of "Volume 3 Number 4 in 1992 of New Material", which is cited in the written objection to JP Appl. H11-377207 by Morita

AAF- Translation of pages 51 to 54 of "Volume 22 Number 104 in 1991 of Electronic ceramics", which is cited in the written objection to JP Appl. H11-377207 by Morita

AAG- Translation of pages 733-737 of "Volume 26 Number 8 in 1991 of ceramics", which is cited in the written objection to JP Appl. H11-377207 by Morita

AAH- Translation of pages 679-681 of "Volume 29 Number 8 in 1994 of ceramics", which is cited in the written objection to JP Appl. H11-377207 by Morita

AAI- Translation of "fine ceramics catalog '96", which is cited in the written objection to JP Appl. H11-377207 by Morita

AAJ- Translation of pages 610 to 616 of "Volume 34 Number 8 in 1997 of J. Soc. Powder Technol. Japan, Thus a powder is produced", which is cited in the written objection to JP Appl. H11-377207 by Morita

AAK- Translation of pages 226 to 230 of "Volume 15 Number 10 in 1997 of Fine ceramics report", which is cited in the written objection to JP Appl. H11-377207 by Morita

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Docket No.

221158US90 DCT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Yasutaka ITO, et al.

SERIAL NO: 10/088,098

GAU: 3742

FILED: May 30, 2002

EXAMINER: FUQUA, Shawntina T.

FOR: CERAMIC SUBSTRATE FOR SEMICONDUCTOR MANUFACTURE/INSPECTION APPARATUS, CERAMIC HEATER, ELECTROSTATIC CLAMPLESS HOLDER, AND SUBSTRATE FOR WAFER PROBER

**INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97**

COMMISSIONER FOR PATENTS  
ALEXANDRIA, VIRGINIA 22313

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**REFERENCES**

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**RELATED CASES**

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- A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

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- No item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this statement.

**DEPOSIT ACCOUNT**

- Please charge any additional fees for the papers being filed herewith and for which no check or credit card payment is enclosed herewith, or credit any overpayment to deposit account number 15-0030. A duplicate copy of this sheet is enclosed.

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180.00 OP

Respectfully submitted,

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<p>Form PTO 1440 (Modified)</p> <p>DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE</p> <p>APR 09 2004</p> <p>LIST OF REFERENCES CITED BY APPLICANT</p> <p>U.S. PATENT &amp; TRADEMARK OFFICE</p>		ATTY DOCKET NO. 221158US90PCT		SERIAL NO. 10/088,098			
		APPLICANT Yasutaka ITO, et al.					
		FILING DATE May 30, 2002		GROUP 3742			
		U.S. PATENT DOCUMENTS					
		EXAMINER INITIAL <i>Sly</i>		DOCUMENT NUMBER AA 6,507,006	DATE 1/14/03	NAME Hiramatsu, et al.	CLASS 
		AB 6,465,763	10/15/02	Ito, et al.			
		AC 6,677,557	1/13/04	Ito et al			
		AD 6,710,307	3/23/04	Ito, et al.			
		AE 6,475,606	11/5/02	Niwa			
		AF US2002/0043527	4/18/02	Ito			
<i>Sly</i>		AG US2003/0015521	1/23/03	Ito			
AH							
AI							
AJ							
AK							
AL							
AM							
AN							
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION		
	AO				YES	NO	
	AP						
	AQ						
	AR						
	AS						
	AT						
	AU						
	AV						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
	AW						
	AX						
	AY						
	AZ						
<input type="checkbox"/> Additional References sheet(s) attached							
Examiner	<i>Shawntina Fugua</i>			Date Considered <i>6/28/04</i>			
<p>*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>							



### LIST OF RELATED CASES

<u>Docket Number</u>	<u>Serial or Patent Number</u>	<u>Filing or Issue Date</u>	<u>Inventor/Applicant</u>
PER CLIENT	09/471,759	12/23/99	SAITO et al.
PER CLIENT	09/462,067	01/05/01	FURUKAWA et al.
PER CLIENT	10/345,356	01/16/03	ITO
PER CLIENT	09/787,954	03/23/01	ITO
PER CLIENT	09/787,816	03/23/01	ITO
PER CLIENT	09/787,818	03/23/01	ITO
PER CLIENT	09/806,957	04/06/01	ITO et al.
PER CLIENT	09/926,730	04/16/01	HIRAMATSU et al.
PER CLIENT	09/880,742	06/13/01	SAITO et al.
PER CLIENT	09/880,359	06/13/01	SAITO et al.
PER CLIENT	09/880,379	06/13/01	SAITO et al.
PER CLIENT	09/915,418	07/27/01	ITO
PER CLIENT	09/916,682	07/30/01	ITO
PER CLIENT	09/890,358	07/30/01	ITO
PER CLIENT	09/917,749	07/31/01	ITO
PER CLIENT	09/958,689	10/10/01	FURUKAWA et al.
PER CLIENT	09/979,676	11/05/01	ZHOU
PER CLIENT	10/048,894	02/01/02	FURUKAWA
PER CLIENT	10/049,539	11/07/01	ZHOU
PER CLIENT	10/182,009	07/24/02	ZHOU

\*Present Application; listed for information

# Abandoned Application

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PER CLIENT	10/222,928	08/19/02	ITO
PER CLIENT	10/265,413	10/07/02	OHASHI et al.
PER CLIENT	10/356,519	02/03/03	ITO
PER CLIENT	10/217,029	08/13/02	ITO
205232US90 PCT	09/806,477	06/25/01	ITO et al.
205235US90 PCT	09/831,887	05/23/01	ITO et al.
205240US90 PCT	09/807,960	05/18/01	HIRAMATSU et al.
205295US90 PCT <sup>#</sup>	09/806,478	07/26/01	ITO et al.
209243US90 PCT	6,507,006	01/14/03	HIRAMATSU et al.
211598US90 PCT	09/869,321	10/18/01	ZHOU
212145US90 PCT	6,465,763	10/15/02	ITO et al.
212814US90 PCT	09/926,012	10/24/01	HIRAMATSU et al.
213163US90 PCT	09/926,092	12/27/01	ITO et al.
214768US90 PCT	09/926,297	12/26/01	HIRAMATSU et al.
214810US90 PCT	09/926,296	12/27/01	ITO et al.
215240US90 PCT	09/926,362	01/16/02	HIRAMATSU et al.
215648US90 PCT	09/926,465	02/12/02	FURUKAWA et al.
215811US90 PCT	09/926,464	01/10/02	HIRAMATSU et al.
215899US90 PCT	09/926,499	03/26/02	HIRAMATSU et al.
216714US90 PCT	09/926,714	03/05/02	ITO et al.
216723US90 PCT	09/926,713	03/05/02	HIRAMATSU
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217551US90 PCT	10/019,448	04/08/02	ITO et al.
217562US90 PCT	09/926,800	03/19/02	HIRAMATSU et al.

\*Present Application; listed for information

<sup>#</sup> Abandoned Application

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217827US90 PCT	10/019,444	04/23/02	HIRAMATSU et al.
217856US90 PCT	6,677,557	01/13/04	ITO et al.
217960US90 PCT	10/019,311	04/09/02	HIRAMATSU et al.
218478US90 PCT	10/030,123	05/16/02	HIRAMATSU et al.
219288US90 PCT	10/049,293	04/30/02	ITO et al.
219289US90 PCT	10/069,943	07/10/02	ITO et al.
219421US90 PCT	10/048,490	04/30/02	ITO et al.
219574US90 PCT	10/048,979	04/26/02	HIRAMATSU et al.
219658US90 PCT	10/048,989	05/29/02	HIRAMATSU et al.
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220254US90 PCT	10/069,510	06/20/02	HIRAMATSU et al.
221014US90 PCT	10/070,443	06/24/02	HIRAMATSU et al.
221015US90 PCT	10/070,441	06/26/02	ITO et al.
221158US90 PCT*	10/088,098	05/30/02	ITO et al.
221160US90 PCT	10/088,100	06/26/02	IDO
221689US90 DIV	6,710,307	03/23/04	ITO et al.
222661US90 PCT	10/111,980	06/27/02	ITO et al.
223945US90 PCT	10/168,527	10/18/02	HIRAMATSU et al.
225895US90 PCT	10/181,724	09/27/02	HIRAMATSU et al.
226831US90 CIP	10/226,160	08/23/02	ITO et al.
226886US90 CIP	10/229,177	08/28/02	HIRAMATSU et al.
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\*Present Application; listed for information

# Abandoned Application

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232736US90 CONT	10/346,095	01/17/03	ITO et al.
233544US90 PCT	10/343,747	08/27/03	ITO et al.
233936US90 PCT	10/344,148	07/29/03	KARIYA et al.
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234735US90 CONT	10/387,452	03/14/03	ITO et al.
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236147US90 PCT	10/398,393	01/21/04	HIRAMATSU et al.
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237386US90	6,475,606	11/05/02	NIWA
237387US90 CONT	10/260,360	10/01/02	NIWA
237457US90 CONT	10/615,950	07/10/03	HIRAMATSU et al.
237934US90 PCT	10/416,497	12/11/03	HIRAMATSU et al.
238745US90 CONT	10/618,651	07/15/03	ITO et al.
238750US90 CONT	10/618,623	07/15/03	ITO et al.
238755US90 CONT	10/618,655	07/15/03	ITO et al.
238761US90 CONT	10/618,665	07/15/03	ITO et al.
238955US90 PCT	10/432,639	11/06/03	ITO et al.
239930US90 PCT	10/380,327	03/13/03	HIRAMATSU et al.
240245US90 CONT	10/619,567	07/16/03	HIRAMATSU et al.
240514US90 CONT	10/362,941	04/28/03	ITO
240648US90 DIV	10/624,589	07/23/03	FURUKAWA et al.
241056US90#	09/524,010	03/13/00	NIWA

\*Present Application; listed for information

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241058US90 CONT#	09/946,463	09/06/01	NIWA
241064US90 CONT	10/244,008	09/16/02	NIWA
241191US90 CONT	10/670,354	09/26/03	NIWA
242402US90 CONT	10/658,454	09/10/03	ITO et al.
242768US90 CONT	10/663,681	09/17/03	ITO et al.
243468US90 PCT	10/473,585	02/13/04	ITO et al.
244440US90 CONT	10/697,287	10/31/03	ITO et al.
245199US90 CONT	10/718,535	11/24/03	HIRAMATSU et al.
246481US90 PCT	09/673,953	12/21/00	ITO et al.
247814US90 CONT	10/759,083	01/20/04	HIRAMATSU et al.

\*Present Application; listed for information

# Abandoned Application

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246909US90

**LIST OF RELATED CASES**

<u>Docket Number</u>	<u>Serial or Patent Number</u>	<u>Filing or Issue Date</u>	<u>Inventor/Applicant</u>
221158US2 PCT <i>86</i>	10/088,098	05/30/02	ITO, et al.
246590US90 DIV <i>87</i>	10/732,296	12/11/03	ITO, et al.
246909US-90-DIV <i>87</i>	10/746,081	12/29/03	HIRAMATSU, et al.
247451US-90-DIV <i>87</i>	10/755,308	01/13/04	HIRAMATSU, et al.
248168US90 CONT <i>87</i>	10/766,027	01/29/04	ITO, et al.

*Shaontina Lague*

*6/27/04*

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Yasutaka ITO, et al.

SERIAL NO: 10/088,098

GAU: 3742

FILED: May 30, 2002

EXAMINER: S. T. Fuqua

FOR: CERAMIC SUBSTRATE FOR SEMICONDUCTOR MANUFACTURE/INSPECTION APPARATUS, CERAMIC HEATER, ELECTROSTATIC CLAMPLESS HOLDER, AND SUBSTRATE FOR WAFER PROBER

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97

COMMISSIONER FOR PATENTS  
ALEXANDRIA, VIRGINIA 22313

SIR:

Applicant(s) wish to disclose the following information.

REFERENCES

- The applicant(s) wish to make of record the references listed on the attached form PTO-1449. Copies of the listed references are attached, where required, as are either statements of relevancy or any readily available English translations of pertinent portions of any non-English language references.
- A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

RELATED CASES

- Attached is a list of applicant's pending application(s) which may be related to the present application. A copy of the claims and drawings of the pending application(s) is attached.
- A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

CERTIFICATION

- Each item of information contained in this information disclosure statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.
- No item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this statement.

DEPOSIT ACCOUNT

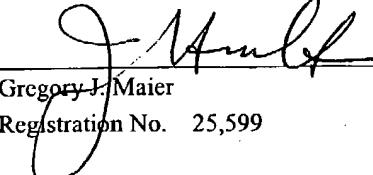
- Please charge any additional fees for the papers being filed herewith and for which no check or credit card payment is enclosed herewith, or credit any overpayment to deposit account number 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

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